ABSTRACT

Provided are a position teaching apparatus and a position teaching method. The position teaching apparatus is used for teaching the position where a wafer transfer mechanism places a wafer into a wafer chuck, comprising: a dummy wafer; a plurality of detection circuits, each detection circuit including a feedback element, wherein, when the feedback element is in contact with the second positioning surface of the wafer chuck, the detection circuit outputs a first feedback signal; and when the feedback element is not in contact with the second positioning surface, the detection circuit outputs a second feedback signal; a control device, configured to control the wafer transfer mechanism to hold the dummy wafer, and adjust the position of the dummy wafer in the wafer chuck to allow all detection circuits to output the second feedback signal, thereby maintaining a non-contact state between all feedback elements and the wafer chuck, and generating the center position of the dummy wafer in the state, wherein, the center position of the dummy wafer is taken as the teaching position where the wafer transfer mechanism places the wafer into the wafer chuck. The present invention is used for teaching the position where the wafer transfer mechanism places the wafer into the wafer chuck, thereby ensuring precise alignment between the center of the wafer and the center of the wafer chuck.